

PROCESS FOR FABRICATING A SUBSTRATE FOR THE EPITAXIAL GROWTH OF A LAYER OF A III-N ALLOY BASED ON GALLIUM

Technical field

- [1] The present invention relates to a process for fabricating a substrate for the epitaxial growth of a layer of a III-N alloy based on gallium (i.e. a layer of gallium nitride (GaN), of aluminium gallium nitride (AlGaN) or a layer of indium gallium nitride (InGaN)), to a process for fabricating such a layer of III-N alloy and to a process for fabricating a high-electron-mobility transistor (HEMT) in such a layer of III-N alloy.

Prior art

- [2] III-N semiconductors, in particular gallium nitride (GaN), aluminium gallium nitride (AlGaN) or indium gallium nitride (InGaN), appear to be particularly promising in particular as regards the formation of high-power light-emitting diodes (LEDs) and of electronic devices operating at high frequency, such as high-electron-mobility transistors (HEMTs) or other field-effect transistors (FETs).
- [3] In so far as these III-N alloys are difficult to find in the form of bulk substrates of large size, they are generally formed by heteroepitaxy, i.e. by epitaxy on a substrate made of a different material.
- [4] Selection of such a substrate in particular takes into account the difference in lattice parameter and the difference in coefficient of thermal expansion between the material of the substrate and the III-N alloy. Specifically, the larger these differences, the greater the risk of formation, in the layer of III-N alloy, of crystal defects, such as dislocations, and the greater the risk of generation of high mechanical stresses, liable to cause excessive strains.
- [5] The materials most frequently considered for the heteroepitaxy of III-N alloys are sapphire and silicon carbide (SiC).
- [6] Apart from its smaller difference in lattice parameter with gallium nitride, silicon carbide is particularly preferred for high-power electronic applications because of its thermal conductivity, which is clearly higher than that of sapphire, and which therefore allows the thermal energy generated during component operation to be more easily dissipated.
- [7] In radiofrequency (RF) applications, it is sought to use semi-insulating silicon carbide, i.e. silicon carbide that typically has an electrical resistivity higher than or equal to $10^5 \Omega \cdot \text{cm}$, in order to minimize parasitic losses (generally called RF losses) in the substrate. However, this material is particularly expensive and currently is available only in the form of substrates of limited size.
- [8] Silicon would allow fabricating costs to be drastically decreased and substrates of large size to be accessed, but structures of III-N-alloy-on-silicon type are penalized by RF propagation losses above 20 GHz and by a poor dissipation of heat.
- [9] Composite structures, such as SopSiC or SiCopSiC structures, have also been investigated [1] but have not proved to be entirely satisfactory. These structures comprise a layer of single-crystal silicon or a layer of single-crystal SiC (intended to

form a seed layer for the epitaxial growth of the gallium nitride) on a polycrystalline SiC substrate, respectively. Although polycrystalline SiC is a material that is inexpensive, that is available in the form of substrates of large size and that dissipates heat well, these composite structures are penalized by the presence of a layer of silicon oxide at the interface between the layer of single-crystal silicon or SiC and the polycrystalline SiC substrate, which forms a thermal barrier hindering the dissipation of heat from the layer of III-N alloy to the polycrystalline SiC substrate.

Brief description of the invention

- [10] One aim of the invention is therefore to remedy the aforementioned drawbacks and in particular limitations related to the size and cost of semi-insulating SiC substrates.
- [11] The aim of the invention is therefore to provide a process for fabricating a substrate for the epitaxial growth of a III-N alloy based on gallium, in particular with a view to forming HEMTs or other high-frequency, high-power electronic devices in which RF losses may be minimized and the dissipation of heat may be maximized.
- [12] An aspect of the invention provides a process for fabricating a substrate for epitaxial growth of a layer of gallium nitride (GaN), of aluminium gallium nitride (AlGaN) or of indium gallium nitride (InGaN), comprising the following successive steps:
 - providing a single-crystal silicon-carbide donor substrate,
 - implanting ionic species into the donor substrate so as to form a weakened region that defines a thin layer of single-crystal SiC to be transferred,
 - bonding the donor substrate to a first receiver substrate via a bonding layer,
 - detaching the donor substrate along the weakened region so as to transfer the thin layer of SiC to the first receiver substrate,
 - performing epitaxial growth of a layer of semi-insulating SiC having a thickness larger than 1 μm on the thin layer of SiC,
 - bonding the layer of semi-insulating SiC to a second receiver substrate, said second receiver substrate having a high electrical resistivity,
 - removing at least one portion of the bonding layer so as to detach the first receiver substrate,
 - removing the transferred thin layer of single-crystal SiC, so as to uncover the layer of semi-insulating SiC.
- [13] By “high-frequency”, what is meant in the present text is a frequency higher than 3 kHz.
- [14] By “high-power”, what is meant in the present text is a power higher than 0.5 W/mm injected through the gate of the transistor.
- [15] By “high electrical resistivity”, what is meant in the present text is an electrical resistivity higher than or equal to 100 $\Omega\cdot\text{cm}$.
- [16] By “semi-insulating SiC”, what is meant in the present text is silicon carbide having an electrical resistivity higher than or equal to $10^5 \Omega\cdot\text{cm}$.
- [17] This process allows a substrate, based on silicon or another low-cost material of high electrical resistivity available in large size, comprising a layer of semi-insulating SiC

having a crystal quality suitable for the subsequent epitaxial growth of a layer of III-N alloy to be formed and the final structure to benefit from the good properties thereof as regards the dissipation of heat and the limitation of RF losses. Since the layer of semi-insulating SiC makes direct contact with the silicon substrate (or substrate of another material of high electrical resistivity), the structure further contains no thermal barrier.

- [18] A process that consisted in forming the layer of semi-insulating SiC by epitaxy directly on a silicon substrate of high electrical resistivity would lead to the formation of a high number of dislocations in the semi-insulating SiC because of the difference in lattice parameter between silicon and silicon carbide. In contrast, the process according to embodiments of the invention makes it possible to use, as seed for the growth of the semi-insulating SiC, a layer of single-crystal SiC the quality of which may be optimal because it was obtained via transfer from the donor substrate.
- [19] Moreover, the use of the first receiver substrate, which plays the role of temporary carrier, may allow the silicon face of the SiC to be oriented optimally in the various steps of the process.
- [20] According to advantageous but optional features of the process, which may be implemented separately or in any technically possible combination thereof:
- [21] - the first receiver substrate and the donor substrate have a difference in coefficient of thermal expansion smaller than or equal to $3 \times 10^{-6} \text{ K}^{-1}$;
- [22] - the first receiver substrate is an SiC substrate having a crystal quality lower than that of the donor substrate;
- [23] - the thin layer of single-crystal SiC transferred to the first receiver substrate has a thickness smaller than $1 \text{ }\mu\text{m}$;
- [24] - the bonding layer is formed from a material that remains thermally stable during the epitaxial growth of the layer of semi-insulating SiC and that is able to be removed from the interface between the transferred layer of single-crystal SiC and the first receiver substrate;
- [25] - the bonding layer is a layer of silicon nitride or of gallium nitride;
- [26] - removing at least one portion of the bonding layer comprises a chemical etch, a delamination by laser and/or the application of a mechanical stress;
- [27] - the layer of semi-insulating SiC is formed by doping with vanadium during the epitaxial growth of the SiC;
- [28] - the layer of semi-insulating SiC is formed by simultaneously depositing silicon, carbon and vanadium;
- [29] - the second receiver substrate is a silicon substrate having an electrical resistivity higher than or equal to $100 \text{ }\Omega\cdot\text{cm}$;
- [30] - the epitaxial layer of semi-insulating SiC has a thickness comprised between 1 and $5 \text{ }\mu\text{m}$;
- [31] - the second receiver substrate is a polycrystalline SiC substrate or a polycrystalline AlN substrate having an electrical resistivity higher than or equal to $100 \text{ }\Omega\cdot\text{cm}$;
- [32] - the epitaxial layer of semi-insulating SiC has a thickness smaller than or equal to $80 \text{ }\mu\text{m}$;

- [33] - the process further comprises a step of recycling the segment of the donor substrate detached from the transferred layer, with a view to forming a new donor substrate;
- [34] - the ionic species are implanted through the silicon face of the donor substrate, and the silicon face of the donor substrate is bonded to the first receiver substrate, so that, after the transferred thin layer of single-crystal SiC has been removed, the silicon face of the layer of semi-insulating SiC is uncovered.
- [35] Another aspect of the invention provides a process for fabricating by epitaxy a layer of gallium nitride.
- [36] Said process comprises:
 - providing a substrate fabricated using the process such as described above,
 - performing epitaxial growth of the layer of gallium nitride on the layer of semi-insulating SiC of said substrate.
- [37] In certain embodiments, the layer of gallium nitride has a thickness comprised between 1 and 2 μm .
- [38] Another aspect of the invention provides a process for fabricating a high-electron-mobility transistor (HEMT).
- [39] Said process comprises:
 - fabricating by epitaxy a layer of gallium nitride, of aluminium gallium nitride or of indium gallium nitride using the process such as described above,
 - forming a heterojunction by epitaxy, on said layer, of a layer of a III-N material different from the material of said layer,
 - forming a channel of the transistor level with said heterojunction,
 - forming a source, a drain and a gate of the transistor on the channel.

Brief description of the drawings

- [40] Further features and advantages of the invention will become apparent from the following detailed description, with reference to the appended drawings, in which:
- [41] [Fig 1] is a schematic cross-sectional view of a single-crystal SiC donor substrate;
- [42] [Fig 2] is a schematic cross-sectional view of the donor substrate of Figure 1, in which substrate a weakened region has been formed by implanting ionic species in order to define a thin layer to be transferred;
- [43] [Fig 3] is a schematic cross-sectional view of a temporary carrier covered with a removable bonding layer;
- [44] [Fig 4] is a schematic cross-sectional view of the temporary carrier of Figure 3 being joined to the donor substrate of Figure 2 via the removable bonding layer;
- [45] [Fig 5] is a schematic cross-sectional view of the donor substrate being detached along the weakened region in order to transfer the thin layer of single-crystal SiC to the temporary carrier;
- [46] [Fig 6] is a schematic cross-sectional view of the thin layer of single-crystal SiC transferred to the temporary carrier after its free surface has been polished;

- [47] [Fig 7] is a schematic cross-sectional view of a layer of semi-insulating SiC being formed by epitaxy on the transferred thin layer of single-crystal SiC;
- [48] [Fig 8] is a schematic cross-sectional view of the structure of Figure 7 being joined to a receiver substrate via the epitaxial layer of semi-insulating SiC;
- [49] [Fig 9] is a schematic cross-sectional view of the removal of the temporary carrier from the structure of Figure 8;
- [50] [Fig 10] is a schematic cross-sectional view of the receiver substrate and of the epitaxial layer of semi-insulating SiC after the thin layer of single-crystal SiC has been removed;
- [51] [Fig 11] is a schematic cross-sectional view of a layer of GaN being formed by epitaxy on the layer of semi-insulating SiC;
- [52] [Fig 12] is a schematic cross-sectional view of a heterojunction being formed by epitaxy of a layer of a III-N alloy different from GaN on the layer of GaN.
- [53] For the sake of legibility of the figures, the various layers have not necessarily been shown to scale.

Detailed description of embodiments

- [54] The invention provides a process for fabricating substrates for the epitaxial growth of binary or ternary III-N alloys based on gallium. Said alloys comprise gallium nitride (GaN), aluminium gallium nitride ($\text{Al}_x\text{Ga}_{1-x}\text{N}$, where $0 < x < 1$, designated in abbreviated form by AlGaN below) and indium gallium nitride ($\text{In}_x\text{Ga}_{1-x}\text{N}$, where $0 < x < 1$, designated in abbreviated form by InGaN below). For the sake of conciseness, in the rest of the text the fabrication of a substrate for the epitaxial growth of a layer of GaN will be described; however, a person skilled in the art will be able to tailor the growth conditions to form a layer of AlGaN or of InGaN, the substrate serving for this epitaxial growth remaining the same.
- [55] The process uses a donor substrate of doped semiconductor single-crystal silicon carbide (SiC), a thin layer of which, transferred to a first receiver substrate, will serve as seed for the growth of a layer of semi-insulating SiC. In the rest of the text, a transfer of the layer via the Smart Cut™ process will be considered; however, it goes without saying that any other layer-transfer technique may be used, for example spalling or laser cutting.
- [56] To this end, a single-crystal SiC substrate having an excellent crystal quality, i.e. in particular a substrate free of dislocations, will be chosen.
- [57] In certain embodiments, the donor substrate may be a bulk substrate of single-crystal SiC. In other embodiments, the donor substrate may be a composite substrate, comprising a superficial layer of single-crystal SiC and at least one other layer of another material. In this case, the layer of single-crystal SiC will have a thickness larger than or equal to 0.5 μm .
- [58] There are various crystal forms (also called polytypes) of silicon carbide. The most common are the forms 4H, 6H and 3C. Preferably, the single-crystal silicon carbide is chosen from the 4H and 6H polytypes, but any polytype may be used to implement the present invention.
- [59] In the figures, a bulk substrate 10 of single-crystal SiC has been shown.

- [60] As known *per se*, as illustrated in Figure 1, such a substrate has a silicon face 10-Si and a carbon face 10-C.
- [61] At the present time, processes of epitaxy of GaN are mainly implemented on the silicon face of the SiC. However, it is not impossible to grow GaN on the carbon face of the SiC. The orientation of the donor substrate (silicon face/carbon face) during the implementation of the method is chosen depending on the face of the SiC intended for the growth of the layer of GaN.
- [62] With reference to Figure 2, ionic species are implanted into the donor substrate 10, so as to form a weakened region 12 that defines a thin layer 11 of single-crystal SiC. The implanted species typically comprise hydrogen and/or helium. A person skilled in the art will be able to define the required implantation dose and energy.
- [63] When the donor substrate is a composite substrate, the implantation is carried out into the surface layer of single-crystal SiC of said substrate.
- [64] Preferably, the ionic species are implanted through the silicon face 10-Si of the donor substrate. As will be seen below, this orientation of the donor substrate makes it possible to put, at the surface of the final substrate intended for the growth of the layer of GaN, the silicon face of the SiC, which is more favourable. However, if it is envisioned to grow the layer of GaN on the carbon face of the SiC, the ionic species must be implanted through the carbon face 10-C of the donor substrate.
- [65] Preferably, the thin layer 11 of single-crystal SiC has a thickness smaller than 1 μm . Specifically, such a thickness is accessible on an industrial scale with the Smart Cut™ process. In particular, the implantation tools available on industrial fabrication lines allow such an implantation depth to be obtained.
- [66] With reference to Figure 3, a first receiver substrate 20 is moreover provided.
- [67] The main function of said first receiver substrate is to temporarily hold the layer 11 of single-crystal SiC between its transfer from the donor substrate and the growth of a layer of semi-insulating SiC on the layer of single-crystal SiC.
- [68] To this end, the first receiver substrate is chosen to have a coefficient of thermal expansion substantially equal to that of the SiC, in order not to generate stresses or strains during the epitaxy of the semi-insulating SiC. Thus, particularly advantageously, the first receiver substrate and the donor substrate (or the layer of single-crystal SiC in the case of a composite donor substrate) have a difference in coefficient of thermal expansion smaller than or equal to $3 \times 10^{-6} \text{ K}^{-1}$.
- [69] Preferably, the first receiver substrate is also made of SiC so as to minimize the difference in coefficient of thermal expansion. Particularly advantageously, the first receiver substrate 20 is an SiC substrate having a crystal quality lower than that of the donor substrate. What is meant by that is that the first receiver substrate may be a polycrystalline SiC substrate, or indeed a substrate of single-crystal SiC but that may comprise dislocations of all types (contrary to the single-crystal SiC of the donor substrate which is chosen for an excellent crystal quality in order to ensure the quality of the epitaxial layer of GaN). Such a substrate of lower crystal quality has the advantage of being less expensive than a substrate of same quality as the donor substrate, while being perfectly adapted to the function of temporary carrier.
- [70] With reference to Figure 4, the donor substrate 10 comprising the thin layer 11 of single-crystal SiC is bonded to the first receiver substrate 20.

- [71] To ensure a good adhesion of the donor substrate to the first donor substrate, a bonding layer 21 is formed at the interface between said substrates.
- [72] In Figure 3, the bonding layer 21 is formed on the first receiver substrate 20, but, in other embodiments that are not illustrated, the bonding layer may be formed on the donor substrate (on the side of the thin layer 11), or indeed partially on the donor substrate and partially on the first receiver substrate.
- [73] The bonding layer is formed from a material that remains thermally stable during the subsequent epitaxial growth of the semi-insulating SiC on the thin layer 11.
- [74] By way of indication, since epitaxy of 4H- or 6H-SiC is carried out at a temperature typically higher than 1500°C, the material of the chosen bonding layer will not degrade or disassociate at such a temperature.
- [75] Moreover, the material of the bonding layer is able to be removed from the interface between the transferred layer of single-crystal SiC and the first receiver substrate 20, for example by means of a selective etch, which is optionally assisted by a plasma.
- [76] According to one preferred embodiment, the bonding layer is a layer of silicon nitride or of gallium nitride. The thickness of said layer is typically comprised between 10 nm and a few hundred nanometres.
- [77] With reference to Figure 5, the donor substrate is detached along the weakened region 12. In a way known *per se*, the detachment may be caused by a heat treatment, a mechanical action, or a combination of these means.
- [78] The effect of this detachment is to transfer the thin layer 11 of single-crystal SiC to the first receiver substrate 20. The remainder 10' of the donor substrate may optionally be recycled with a view to another use.
- [79] As illustrated in Figure 6, the free face of the transferred layer 11 of single-crystal SiC is the carbon face 11-C (the silicon face 11-Si being on the side of the bonding interface). This face is polished, for example by chemical-mechanical polishing (CMP), to remove defects related to the implantation of ionic species and to decrease the roughness of the layer 11.
- [80] With reference to Figure 7, an epitaxial growth of a layer 30 of semi-insulating SiC is performed on the thin layer 11 of single-crystal SiC. The polytype of the semi-insulating SiC is advantageously identical to that of the SiC of the donor substrate.
- [81] This epitaxial growth is performed at a very high temperature, generally higher than 1500°C but, as explained above, the bonding layer 21 is stable at this temperature. In addition, on account of the small difference in coefficient of thermal expansion between the material of the first receiver substrate and the SiC, the mechanical stresses generated in the stack are minimized.
- [82] There are various techniques for forming semi-insulating SiC. According to one embodiment, the layer of SiC is doped with vanadium during its epitaxial growth. According to another embodiment, silicon, carbon and vanadium are simultaneously deposited using suitable precursors in an epitaxial reactor.
- [83] The layer of semi-insulating SiC advantageously has a thickness larger than 1 μm , so as to contribute in a significant way to the dissipation of heat within the final structure. This thickness is larger than the thickness directly accessible with the Smart Cut™ process using industrially available equipment.

- [84] Thus, the process consisting in transferring a layer of single-crystal SiC with a thickness smaller than 1 μm , then in forming a single-crystal layer of single-crystal SiC by epitaxy on said transferred layer, allows the technical limits of the implantation tools that are industrially available to carry out the Smart Cut™ process to be circumvented. Moreover, this process does not require a donor substrate made of semi-insulating SiC (which would be particularly expensive); specifically, since the transferred layer essentially plays the role of a seed layer for forming the heat-dissipating layer made of semi-insulating SiC, the transferred layer may be formed from single-crystal SiC of standard electrical resistivity.
- [85] With reference to Figure 8, a second receiver substrate 40, which has a high electrical resistivity, is provided, and bonded to the layer 30 of semi-insulating SiC. For example, the second receiver substrate may be a silicon substrate having an electrical resistivity higher than or equal to 100 $\Omega\cdot\text{cm}$, a polycrystalline SiC substrate or a polycrystalline AlN substrate, also having an electrical resistivity higher than or equal to 100 $\Omega\cdot\text{cm}$.
- [86] The thickness of the layer 30 of semi-insulating SiC will possibly be chosen depending on the material of the second receiver substrate. Thus, when the second receiver substrate is a silicon substrate of high electrical resistivity, the layer 30 of semi-insulating SiC will advantageously have a thickness comprised between 1 and 5 μm . When the second receiver substrate is made of polycrystalline AlN or polycrystalline SiC, it will possibly be advantageous for the layer 30 of semi-insulating SiC to have a much larger thickness, possibly of up to 80 μm , for example of about 50 to 80 μm , to improve the dissipation of heat within the final structure.
- [87] Next, at least some of the bonding layer 21 is removed so as to detach the first receiver substrate from the rest of the structure. During this removal, the layer 21 must be sufficiently damaged to allow a dissociation from the structure. Any suitable means may be employed. For example, but non-limitingly, the bonding layer may be removed via a chemical etch, a delamination by laser and/or the application of a mechanical stress.
- [88] As illustrated in Figure 9, there therefore remains, at the end of this separation, a structure that consists in succession of the second receiver substrate 40, of the layer 30 of semi-insulating SiC and of the transferred thin layer 11 of single-crystal SiC. Any residues of the bonding layer 21 are removed by polishing and/or etching.
- [89] With reference to Figure 10, the thin layer 11 is removed so as to uncover the layer 30 of semi-insulating SiC. The thin layer 11 may be removed by any suitable means, such as a chemical or mechanical etch.
- [90] The uncovered face is the silicon face of the semi-insulating SiC, which is favourable to the epitaxial growth of GaN. A substrate suitable for epitaxial growth of III-N alloys has thus been formed.
- [91] With reference to Figure 11, a layer 50 of GaN (or, as mentioned above, of AlGaN or InGaN) is grown on the free face of the layer 30 of semi-insulating SiC. The thickness of the layer 50 is typically comprised between 1 and 2 μm .
- [92] Next, as illustrated in Figure 12, a heterojunction is formed by growing, by epitaxy, on the layer 50, a layer 60 of a III-N alloy different from that of the layer 50.
- [93] It is thus possible to continue the fabrication of transistors, in particular of HEMTs, from this heterojunction, using processes known to those skilled in the art, the channel

of the transistor being formed level with the heterojunction, and the source, the drain and the gate of the transistor being formed on the channel.

- [94] The structure thus obtained is particularly advantageous in that it comprises a relatively thick layer of semi-insulating SiC, which on the one hand serves as seed for the epitaxial growth of the layer of III-N alloy and on the other hand both dissipates heat well and limits RF losses. Moreover, the second receiver substrate, which bears the layer of semi-insulating SiC, makes direct contact with said layer, so that the structure does not comprise any thermal barrier.
- [95] Thus, a HEMT or another high-frequency, high-power electronic device, formed in a layer of II-N alloy formed by epitaxy on such a structure, has minimized RF losses and a maximized dissipation of heat.

References

- [96] [1] Comparative study on stress in AlGaIn/GaN HEMT structures grown on 6H-SiC, Si and on composite substrates of the 6H-SiC/poly-SiC and Si/poly-SiC, M. Guziewicz et al, Journal of Physics: Conference Series 100 (2008) 040235

Claims

- [Claim 1] A process for fabricating a substrate for epitaxial growth of a layer of gallium nitride (GaN), of aluminium gallium nitride (AlGaN) or of indium gallium nitride (InGaN), comprising the following successive steps:
- providing a single-crystal silicon-carbide donor substrate,
 - implanting ionic species into the donor substrate so as to form a weakened region that defines a thin layer of single-crystal SiC to be transferred,
 - bonding the donor substrate to a first receiver substrate via a bonding layer,
 - detaching the donor substrate along the weakened region so as to transfer the thin layer of SiC to the first receiver substrate,
 - performing epitaxial growth of a layer of semi-insulating SiC having a thickness larger than 1 μm on the thin layer of SiC,
 - bonding the layer of semi-insulating SiC to a second receiver substrate, said second receiver substrate having a high electrical resistivity,
 - removing at least one portion of the bonding layer so as to detach the first receiver substrate,
 - removing the transferred thin layer of single-crystal SiC, so as to uncover the layer of semi-insulating SiC.
- [Claim 2] The process according to Claim 1, wherein the first receiver substrate and the donor substrate have a difference in coefficient of thermal expansion smaller than or equal to $3 \times 10^{-6} \text{ K}^{-1}$.
- [Claim 3] The process according to either of Claims 1 and 2, wherein the first receiver substrate is an SiC substrate having a crystal quality lower than that of the donor substrate.
- [Claim 4] The process according to one of Claims 1 to 3, wherein the thin layer of single-crystal SiC transferred to the first receiver substrate has a thickness smaller than 1 μm .
- [Claim 5] The process according to one of Claims 1 to 4, wherein the bonding layer is formed from a material that remains thermally stable during the epitaxial growth of the layer of semi-insulating SiC and that is able to be removed from the interface between the transferred layer of single-crystal SiC and the first receiver substrate.
- [Claim 6] The process according to one of Claims 1 to 5, wherein the bonding layer is a layer of silicon nitride or of gallium nitride.
- [Claim 7] The process according to one of Claims 1 to 6, wherein removing at least one portion of the bonding layer comprises a chemical etch, a delamination by laser and/or the application of a mechanical stress.
- [Claim 8] The process according to one of Claims 1 to 7, wherein the layer of semi-insulating SiC is formed by doping with vanadium during the epitaxial growth of the SiC.

- [Claim 9] The process according to one of Claims 1 to 7, wherein the layer of semi-insulating SiC is formed by simultaneously depositing silicon, carbon and vanadium.
- [Claim 10] The process according to one of Claims 1 to 9, wherein the second receiver substrate is a silicon substrate having an electrical resistivity higher than or equal to 100 $\Omega\cdot\text{cm}$.
- [Claim 11] The process according to Claim 10, wherein the epitaxial layer of semi-insulating SiC has a thickness comprised between 1 and 5 μm .
- [Claim 12] The process according to one of Claims 1 to 9, wherein the second receiver substrate is a polycrystalline SiC substrate or a polycrystalline AlN substrate having an electrical resistivity higher than or equal to 100 $\Omega\cdot\text{cm}$.
- [Claim 13] The process according to Claim 12, wherein the epitaxial layer of semi-insulating SiC has a thickness smaller than or equal to 80 μm .
- [Claim 14] The process according to one of Claims 1 to 13, further comprising a step of recycling the segment of the donor substrate detached from the transferred layer, with a view to forming a new donor substrate.
- [Claim 15] The process according to one of Claims 1 to 14, wherein:
- the ionic species are implanted through the silicon face of the donor substrate,
 - the silicon face of the donor substrate is bonded to the first receiver substrate, so that, after the transferred thin layer of single-crystal SiC has been removed, the silicon face of the layer of semi-insulating SiC is uncovered.
- [Claim 16] A process for fabricating by epitaxy a layer of gallium nitride, comprising:
- providing a substrate fabricated using the process according to one of Claims 1 to 15,
 - performing epitaxial growth of the layer of gallium nitride on the layer of semi-insulating SiC of said substrate.
- [Claim 17] The process according to Claim 16, wherein the layer of gallium nitride has a thickness comprised between 1 and 2 μm .
- [Claim 18] A process for fabricating a high-electron-mobility transistor (HEMT), comprising:
- fabricating by epitaxy a layer of gallium nitride, of aluminium gallium nitride or of indium gallium nitride using the process according to either of Claims 16 and 17,
 - forming a heterojunction by epitaxy, on said layer, of a layer of a III-N material different from the material of said layer,
 - forming a channel of the transistor level with said heterojunction,
 - forming a source, a drain and a gate of the transistor on the channel.